

ABSTRACT

A load-lock device for introducing substrates into a vacuum chamber comprises a load-lock chamber with at least one opening on the input side for introducing the substrates from an atmosphere area located in front of the input-side opening into an interior space located inside the load-lock chamber, and at least one opening on the output side for connecting the interior space of the load-lock chamber to the interior space of a vacuum chamber with the intermediary of a valve; at least one vacuum door which is associated with a respective opening on the input side and which comprises a closure element which communicates with a drive device via at least one carrier rod and is adjustable by the drive device between a position in which the input-side opening is open and a position in which the input-side opening is closed and in which the closure element contacts a contact surface of the load-lock chamber, wherein, considered from the atmosphere area located in front of the input-side opening, the drive device is arranged behind a plane which extends through the contact surface of the load-lock chamber and lies vertical to the axis of the input-side opening.